# Monthly LabAdviser update: 27/11 2017

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| Updated Subject | Contributor | Link to the updated pages |
| **KOH etch rates**  In PECVD oxides and TEOS | **Yannick Seis @nbi.ku** | [KOH\_Etch#KOH\_etching\_baths](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/KOH_Etch#KOH_etching_baths) |
| **New spin coater: Gamma E-beam and UV**   * Overview section * Process information | **Thomas Anhøj @danchip** | [Coaters#Spin\_Coater:\_Gamma\_E-beam\_and\_UV](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Coaters#Spin_Coater:_Gamma_E-beam_and_UV)  [Lithography/Coaters/Spin\_Coater:\_Gamma\_E-beam\_and\_UV\_processing](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/Coaters/Spin_Coater:_Gamma_E-beam_and_UV_processing) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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|  | **Manual for Hotplate (SU8)** |
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|  | **Manual for Aligner: MA6 - 2** |
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|  | **Manual for Spin Coater: Gamma e-beam & UV** |
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|  | **Manual for Thermal Evaporator** |
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|  | **Manual for TPT wire bonder** |
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